

Attv. Dkt. No. APPM/008629/FEP/GCM/AG

In re Application of:

Olsen, et al.

Serial No.: 10/736.061

Confirmation No.: 4253

Filed: December 15, 2003

For: **A Method of Forming a
Silicon Oxynitride Layer**

Group Art Unit: 1762

Examiner: Cachet I. Sellman

MAIL STOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

RESPONSE TO FINAL OFFICE ACTION DATED JULY 19, 2006

In response to the Final Office Action dated July 19, 2006, having a shortened statutory period for response set to expire on October 19, 2006, please enter this response and reconsider the claims pending in the application for the reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/008629/KMT for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 4 of this paper.